

Title (en)

VAPOR COLLECTION METHOD AND APPARATUS

Title (de)

VERFAHREN UND VORRICHTUNG ZUM SAMMELN VON DAMPF

Title (fr)

PROCEDE ET APPAREIL DE COLLECTE DE VAPEUR

Publication

EP 1337799 B1 20070228 (EN)

Application

EP 01977798 A 20010921

Priority

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- US 23521400 P 20000924
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- US 27405001 P 20010307

Abstract (en)

[origin: WO0225193A1] A vapor collection method and apparatus capable of capturing vapor compositions without substantial dilution. The method and apparatus utilize a material (12) that has a surface (14) with an adjacent gas phase. A chamber (16) is positioned in close proximity to a surface (14) of the material (12). The position of the chamber (16) creates a relatively small gap (H) between the surface of the material (14) and the chamber (16). The adjacent gas phase between the chamber and the surface define a region possessing an amount of mass. At least a portion of the mass is drawn through the region by induced flow. The utilization of a small gap (H) limits the flow of mass that is external to the chamber (16) from being swept through the chamber by induced flow.

IPC 8 full level

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